

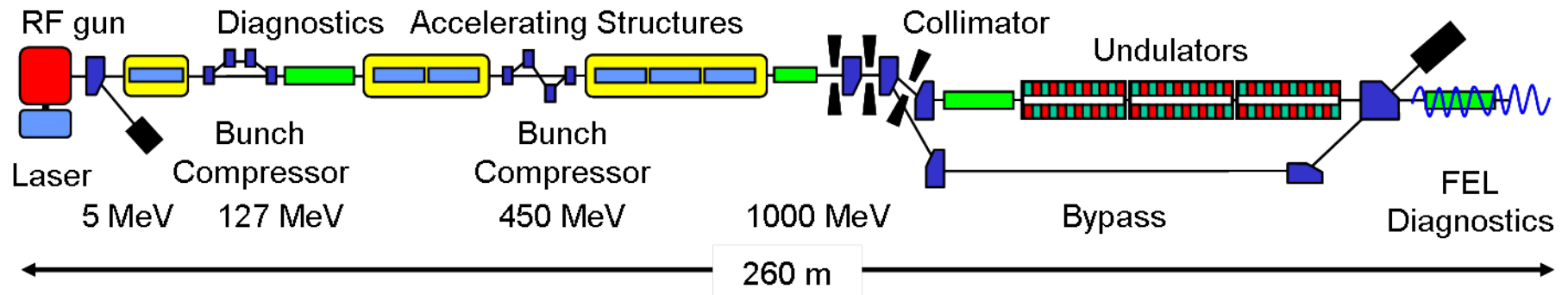
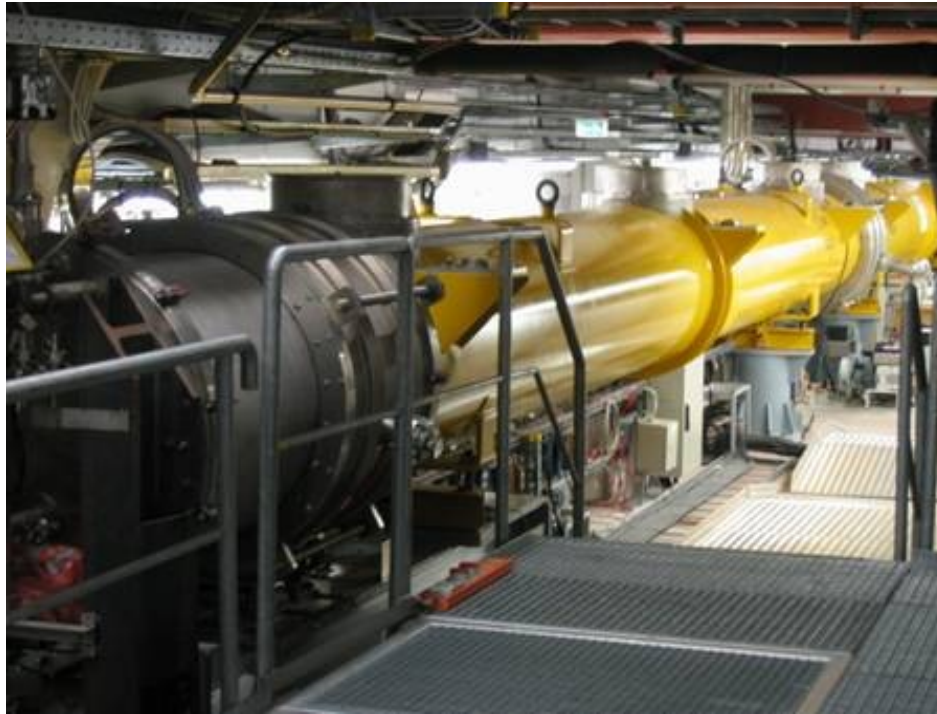
Piezo Control for LFD compensation



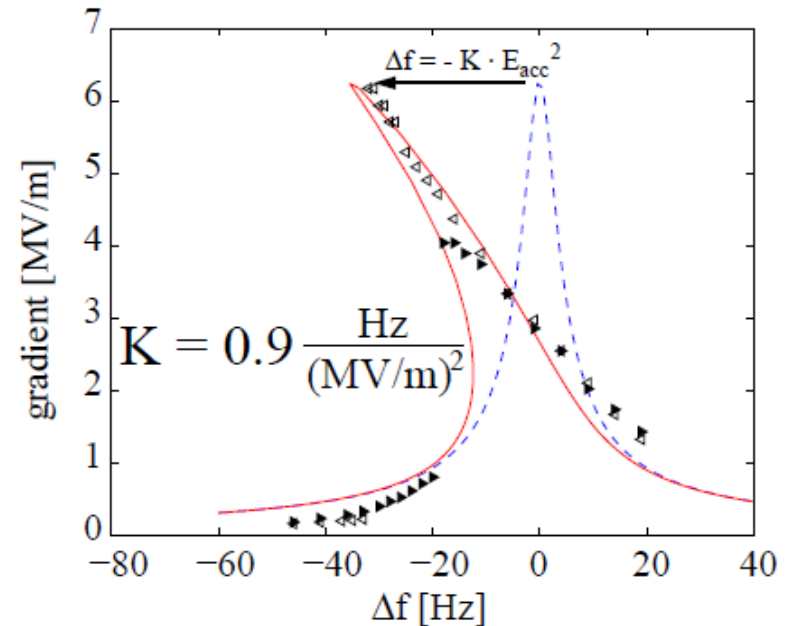
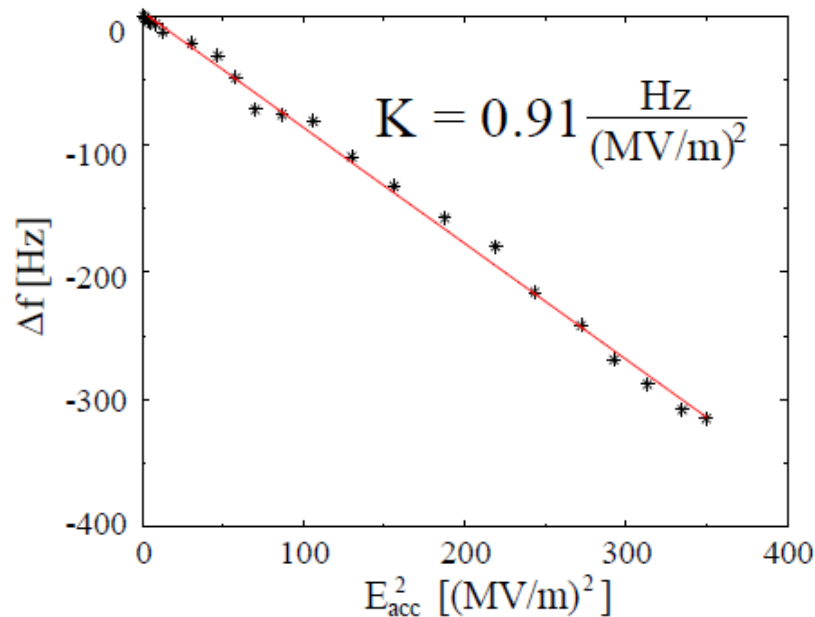
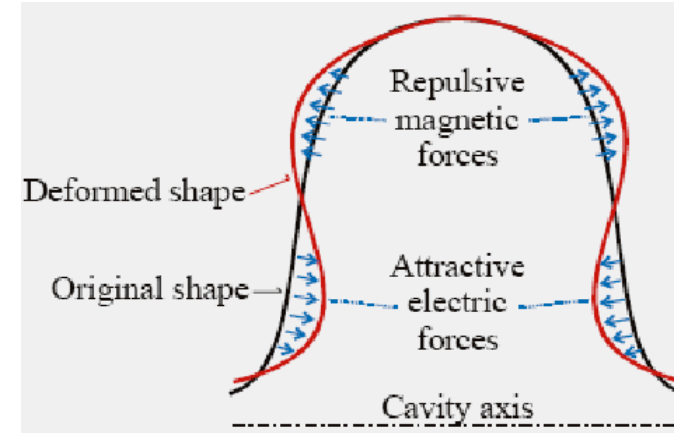
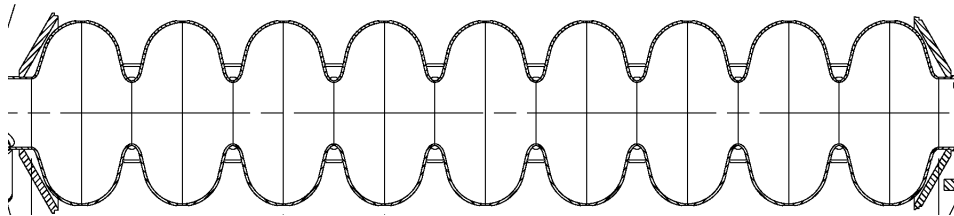
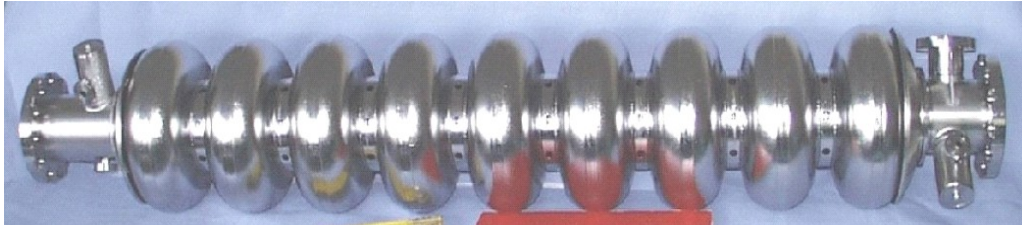
M.Grecki, DESY, Hamburg

K.Przygoda, T.Pozniak,
Technical University of Lodz,
Lodz, Poland

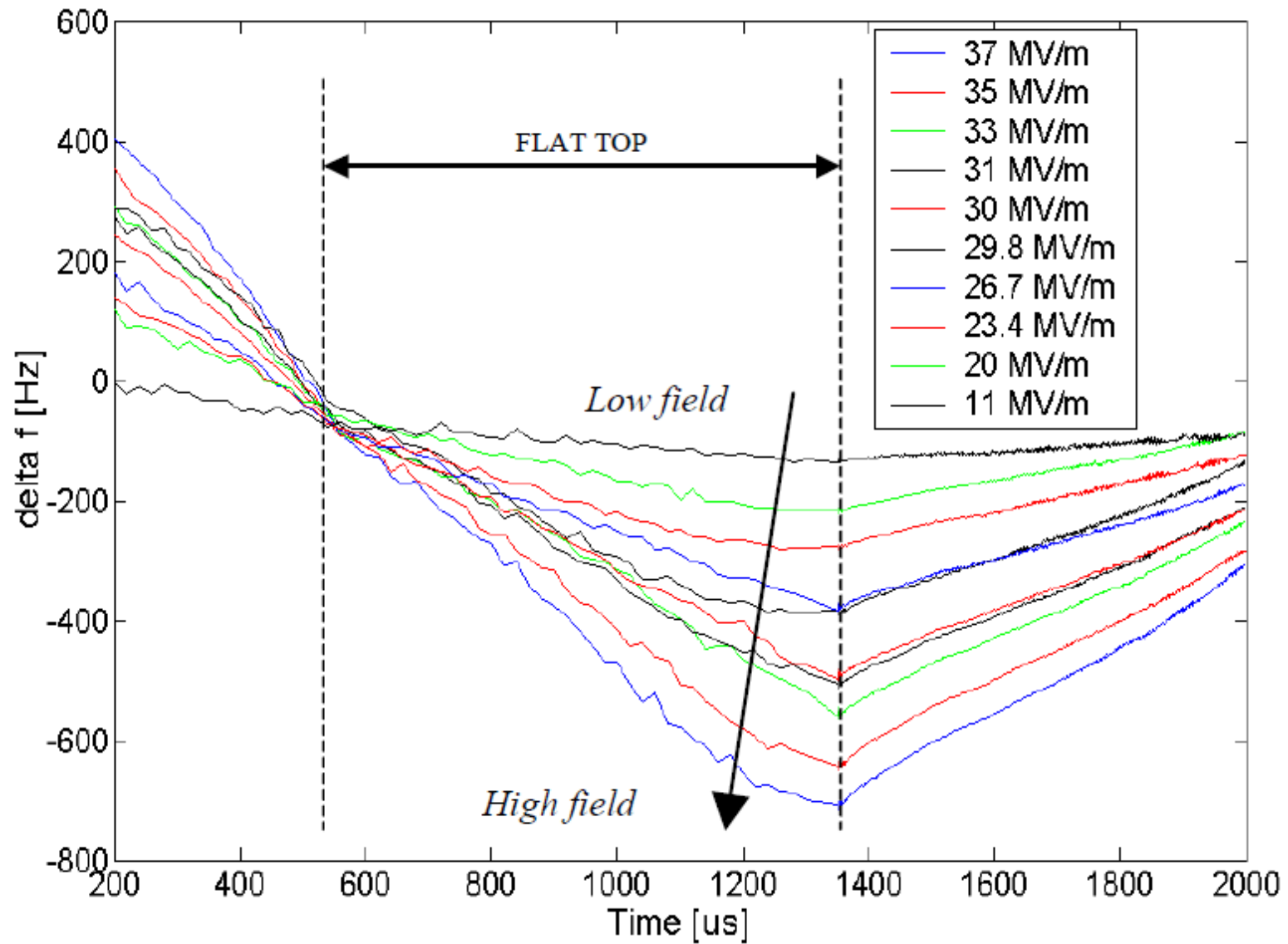
FLASH



Lorentz Force Detuning (LFD)

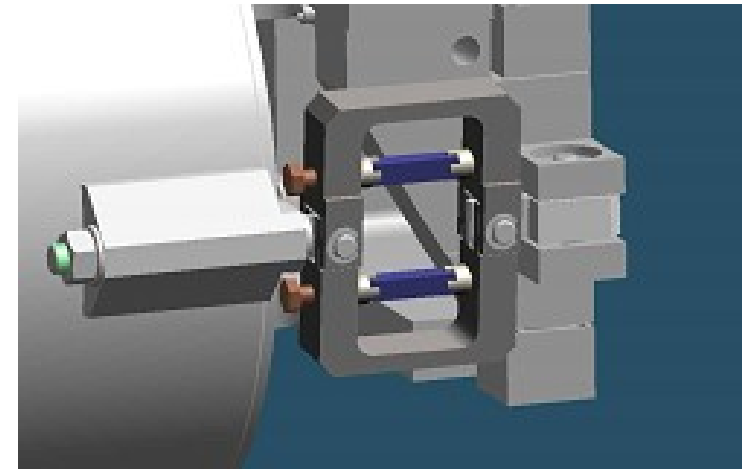


LFD vs gradient

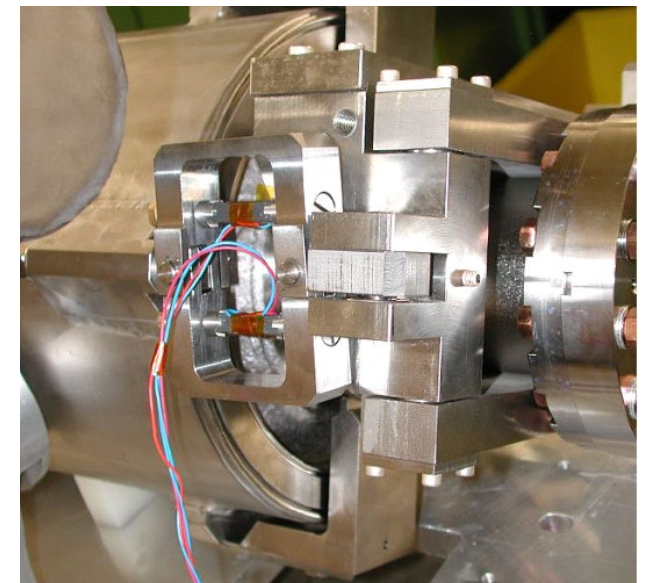


Goals of Piezo Control System

- Drive the piezoelements assembled in fast tuners frames to minimize the Lorentz Force Detuning
- On-line frequency detuning calculation
- Microphonics measurement and compensation



PI Piezo

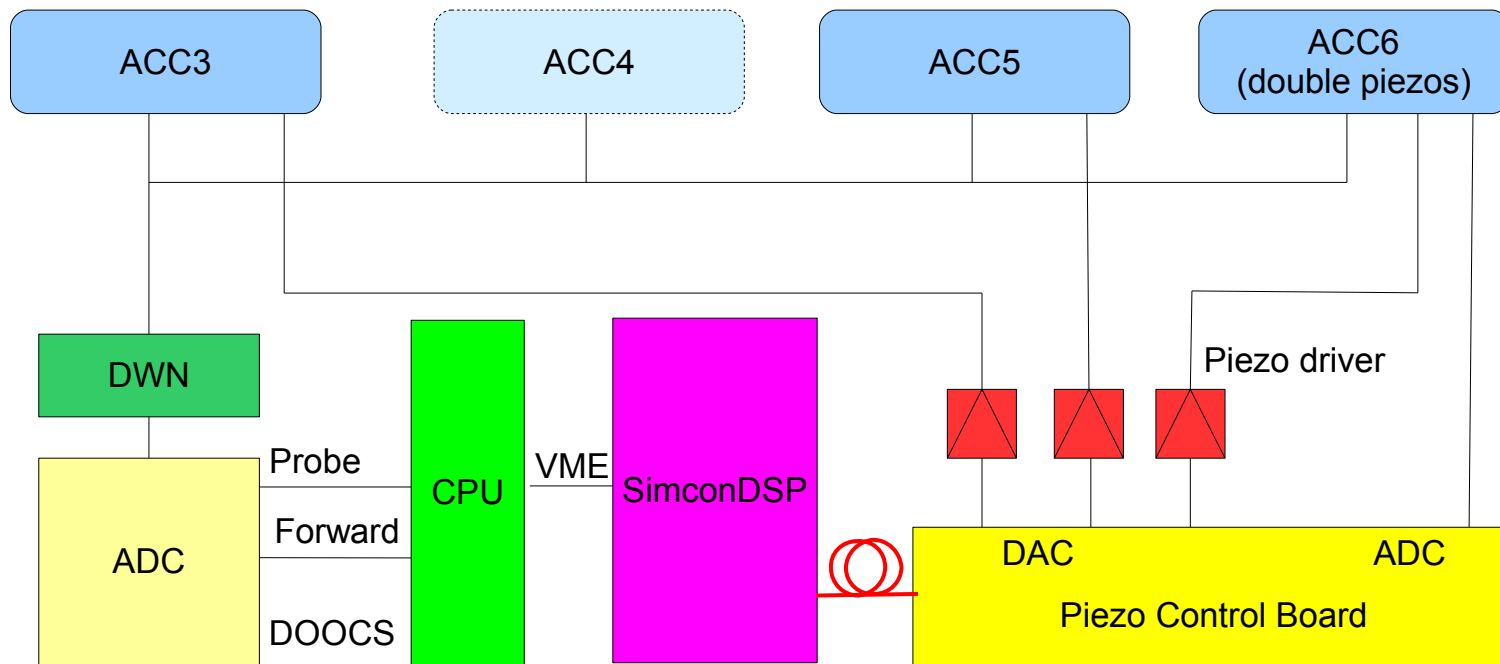
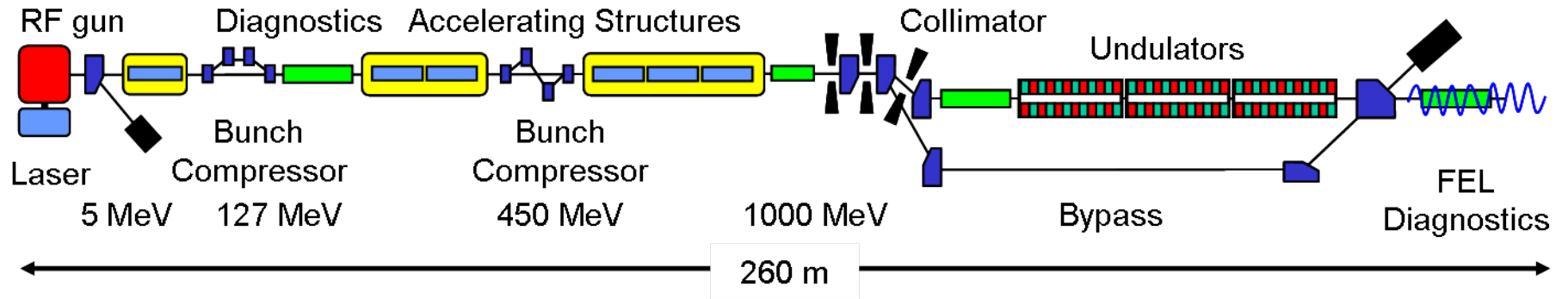


General Requirements of Piezo Control System for FLASH

- Dynamic Lorentz force detuning (LFD) during flat-top $\Delta\omega < 10$ Hz for field up to 30 MV/m (compensation up to 600 Hz with single puls, up to 1kHz with resonant excitation) providing constant offset of $\Delta\omega$ during flat top
- Piezo control must allow to tune/detune cavities in limited range instead of using step motor tuners
- Active attenuation of mechanical vibrations
- Maximum repetition rate of RF (LFD compensation) pulse 10 Hz
- Piezo control must assure piezo lifetime at least 10^{10} pulses (~20 years of operation), piezo must be protected and monitored (it is fragile to over current and over voltage; in particular caused by resonance in the cables)
- Possible microphonics compensation between the RF pulses (sensor/actuator mode)



Piezo tuners at FLASH



Piezos installed in ACC3,5,6

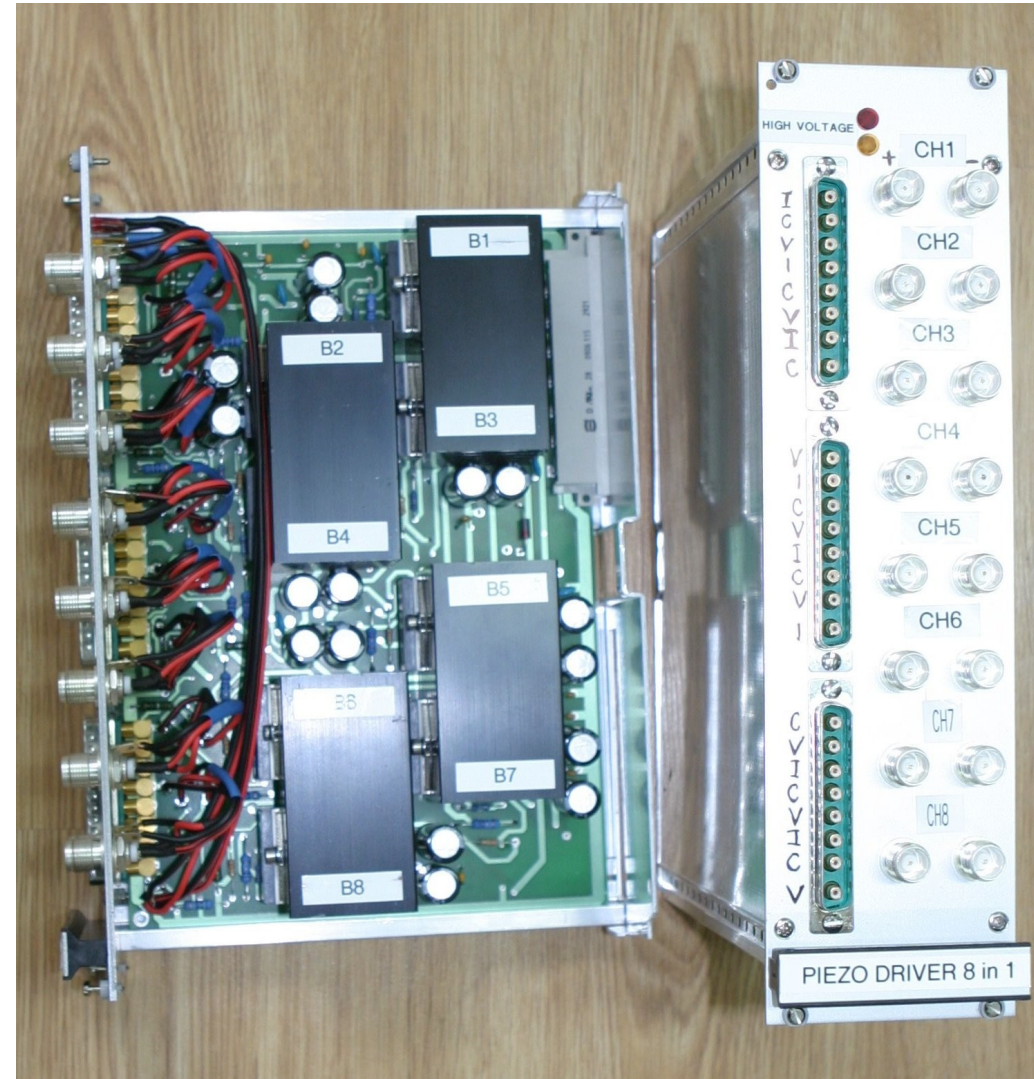
| Producent ratings | Noliac | PI ceramic |
|-------------------|---------------------------------|----------------------|
| Model: | SCMAS/S1/A/10/10/30/200/42/6000 | P-888.90 |
| Cells: | 8 | 8 |
| Voltage: | < 200 V | < 120 V |
| Blocking force: | 6 kN | 3 kN |
| Size: | 10 mm x10 mm x 30 mm | 10 mm x10 mm x 35 mm |
| Capacitance: | 6 μ F | 12 μ F |

Piezos Capacitance at ACC3,5,6

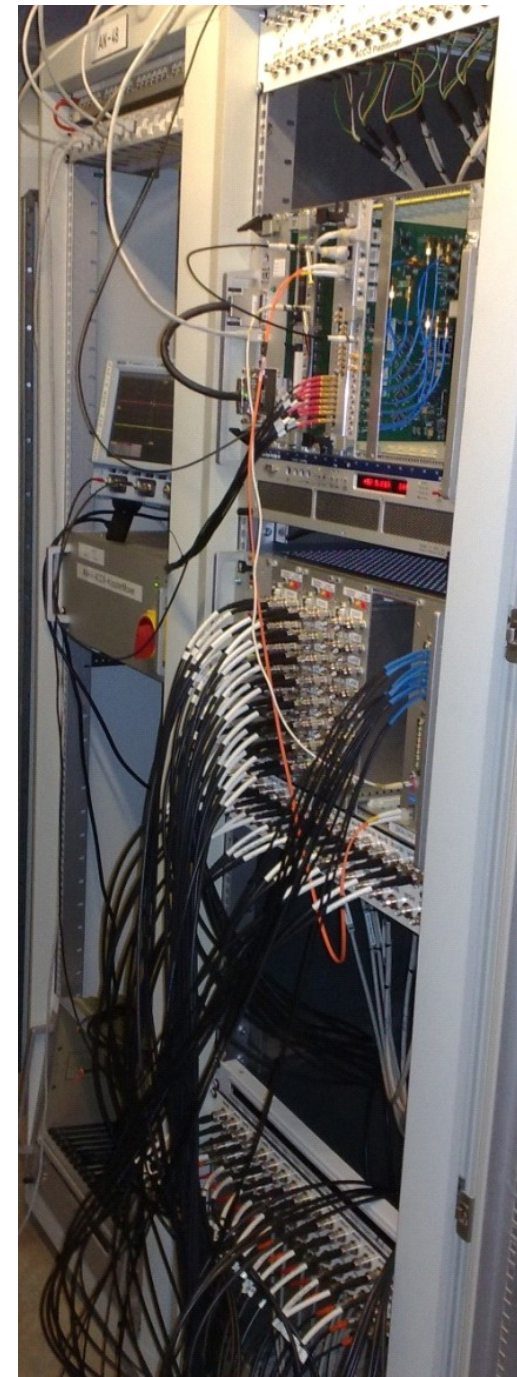
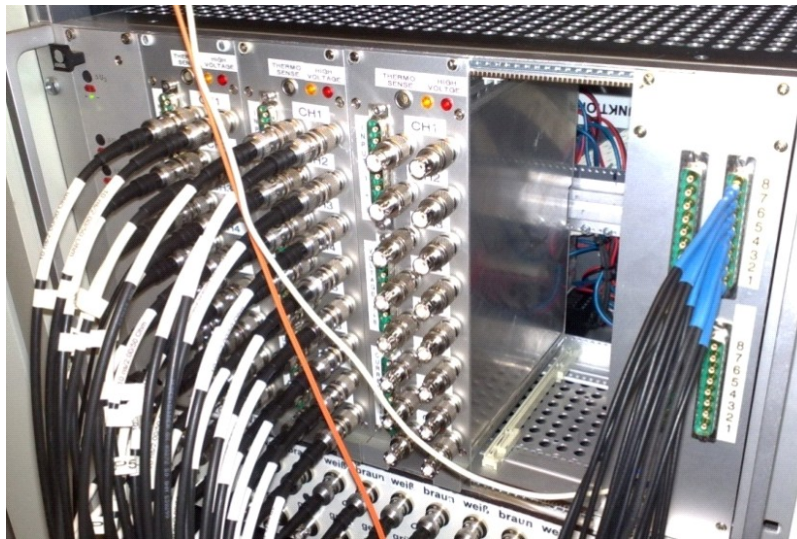
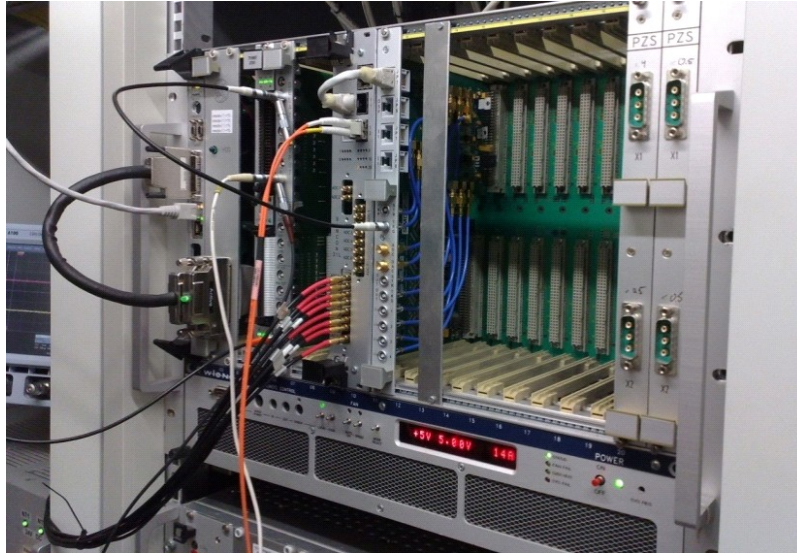
| cavity | piezo | model | ACC3/M7 | model | ACC5/M5 | model | ACC6/M6 |
|--------|-------|--------|-------------|--------|-------------|-------|---------|
| 1 | 1 | PI | 4,93uF | Noliac | 2,1uF | PI | 4,13uF |
| | 2 | - | Unavailable | - | Unavailable | PI | 4,45uF |
| 2 | 1 | PI | 4,61uF | Noliac | 2,22uF | PI | 4,4uF |
| | 2 | - | Unavailable | - | Unavailable | PI | 4,2uF |
| 3 | 1 | PI | 4,91uF | Noliac | 2,28uF | PI | 4,21uF |
| | 2 | - | Unavailable | - | Unavailable | PI | 4,1uF |
| 4 | 1 | PI | 4,6uF | Noliac | 3,12uF | PI | 3,86uF |
| | 2 | - | Unavailable | - | Unavailable | PI | 4,2uF |
| 5 | 1 | Noliac | 2,6uF | Noliac | 2,2uF | PI | 4,22uF |
| | 2 | - | Unavailable | - | Unavailable | PI | 4,28uF |
| 6 | 1 | Noliac | 2,13uF | Noliac | 2,13uF | PI | 3,73uF |
| | 2 | - | Unavailable | - | Unavailable | PI | 4,41uF |
| 7 | 1 | Noliac | 2,22uF | Noliac | 2,19uF | PI | 4,69uF |
| | 2 | - | Unavailable | - | Unavailable | PI | 4,41uF |
| 8 | 1 | Noliac | 2,21uF | Noliac | 2,17uF | PI | 4,31uF |
| | 2 | - | Unavailable | - | Unavailable | PI | 4,2uF |

Piezodriver

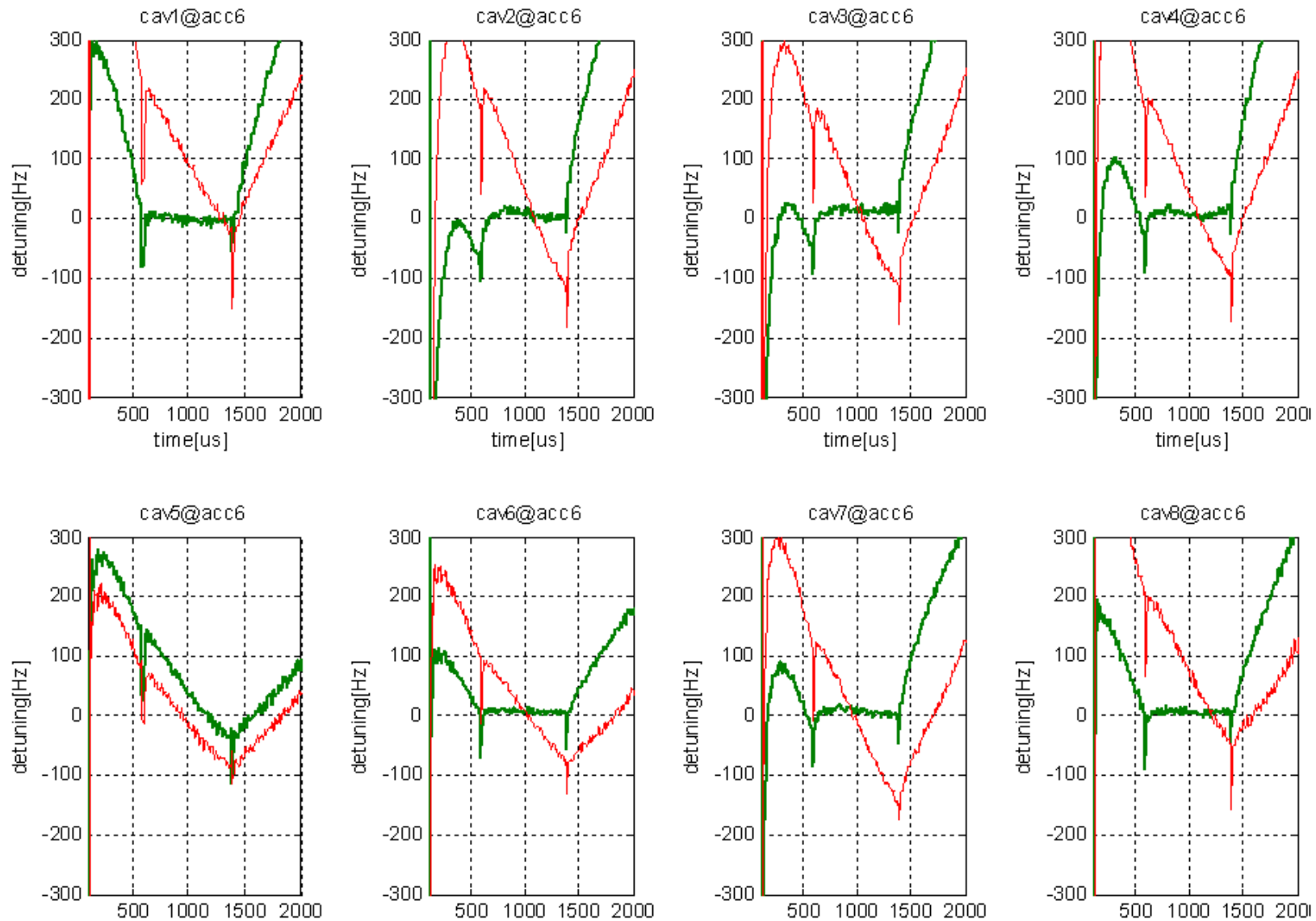
- Suitable for both types of piezostacks up to 5 μ F:
 - Physik Instrumente (P-888.90 PIC255)
 $C_{zk} = 4,4 \mu\text{F}$
 - NOLIAC (SCMAS/S1/A/10/10/20 /200/42/6000)
 $C_{zk} = 2,4 \mu\text{F}$
- Maximal supply voltage up to $\pm 150 \text{ V}$ (nominal operating voltage $\pm 80\text{V}$)
- Input voltage $\pm 1 \text{ V}$
- Amplifier gain $G_u = 100\text{V/V}$,
- Operational temperature $T_c < 75^\circ\text{C}$ ($T_j < 125^\circ\text{C}$)
- Pass-band frequency up to 5 kHz (for load 5 μF)
- Monitoring of output voltage and current
- Single channel PZD with Apex PB51
- 8 channels on single board (Eurocard form factor)
- Up to 4 periods of sinus wave 80V, 200 Hz in 5 μF load, 10 Hz repetition rate (thermal limit)



Piezo Control System at FLASH

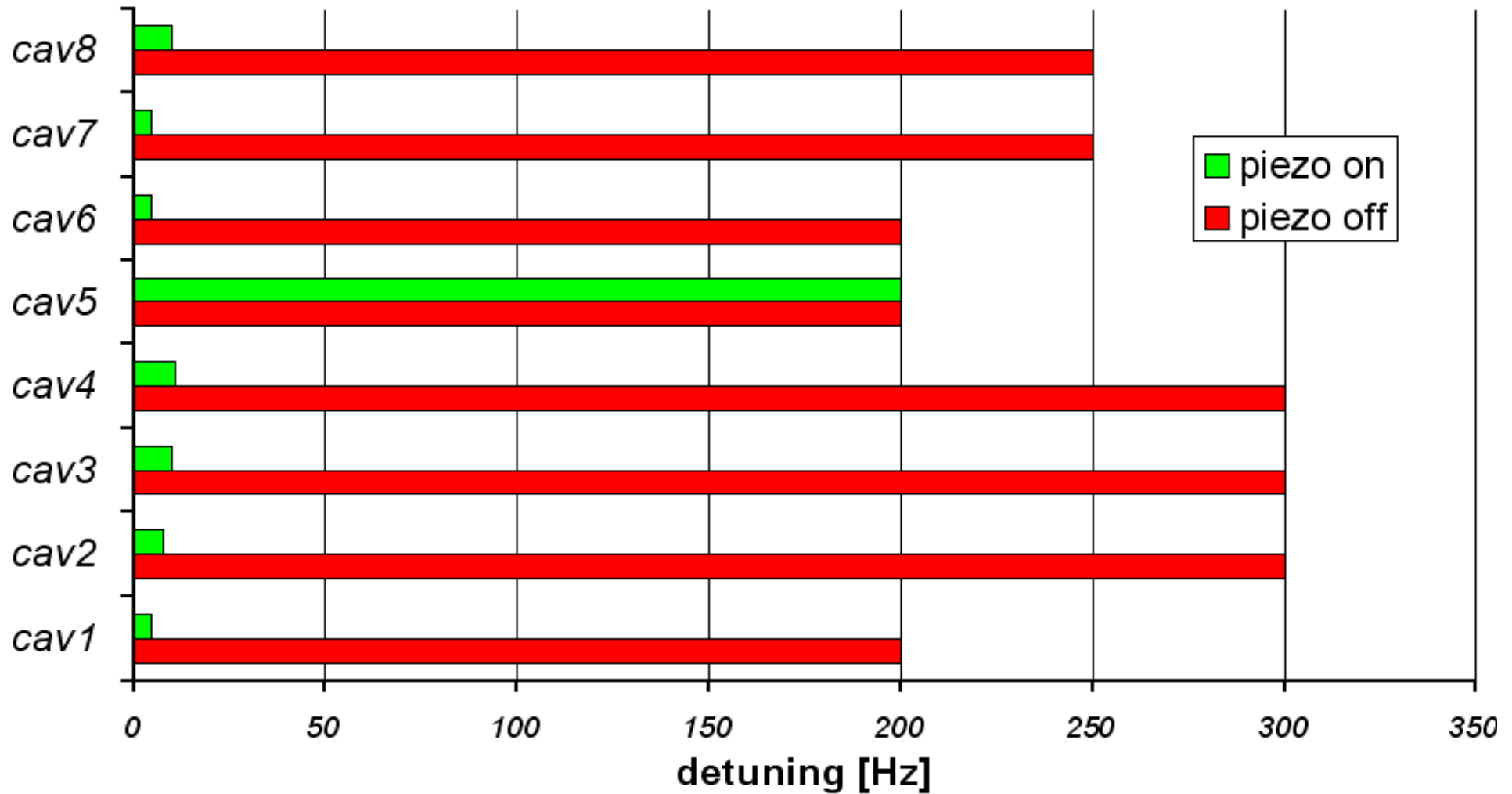


ACC6 (SP = 20 MV/m, rep = 5 Hz)

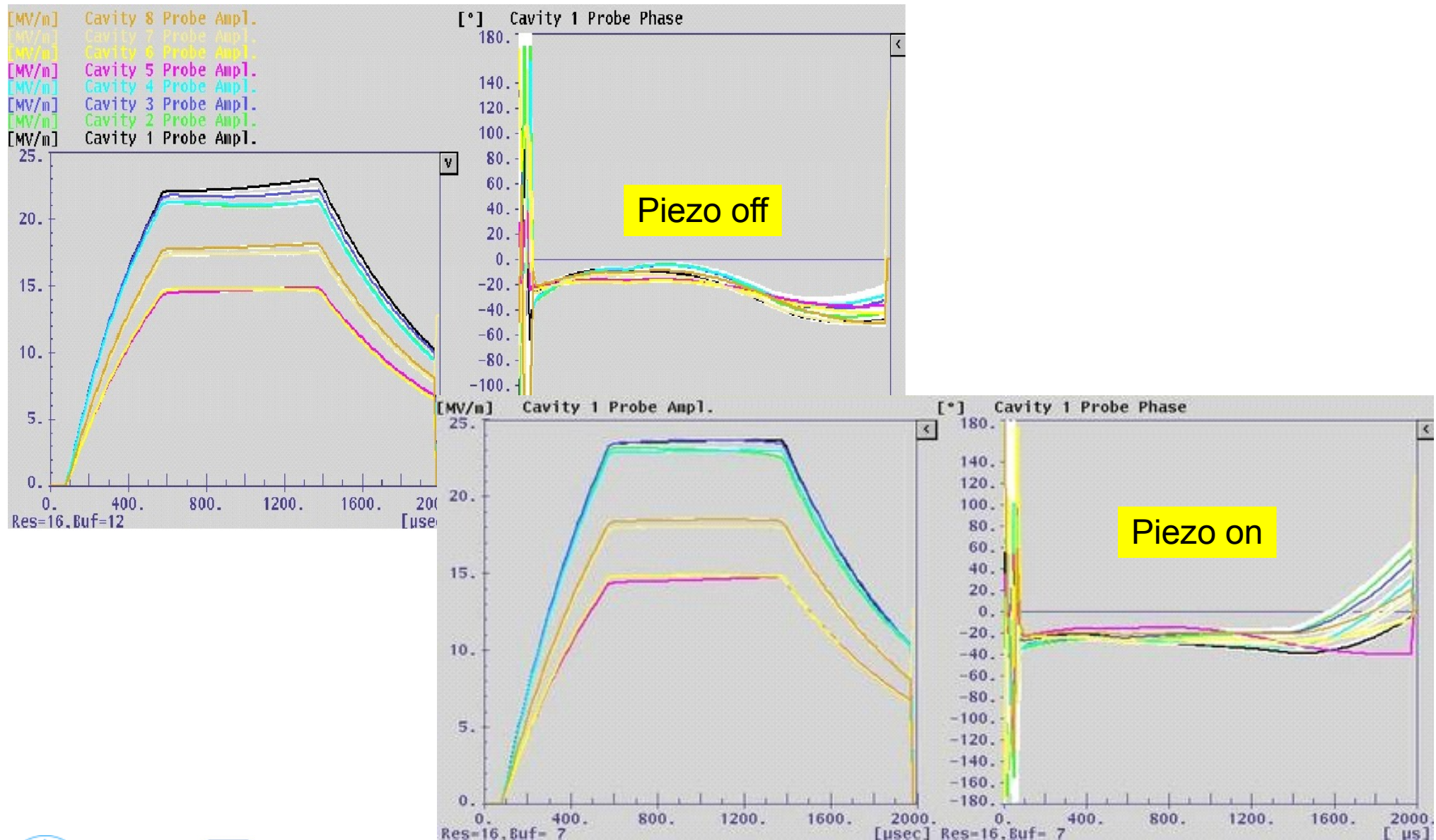


ACC6 (SP = 20 MV/m, rep = 5 Hz)

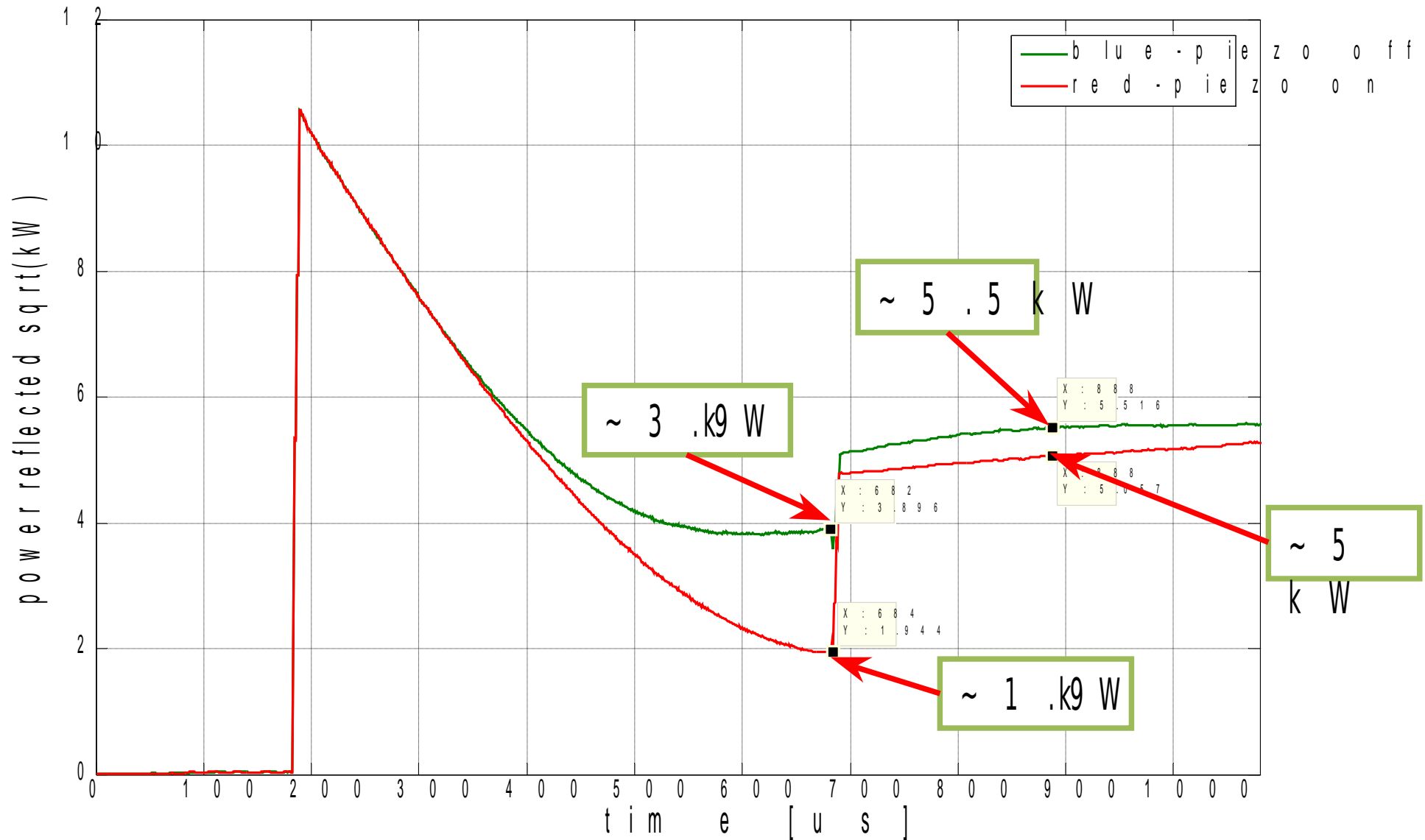
LFD compensation ACC6



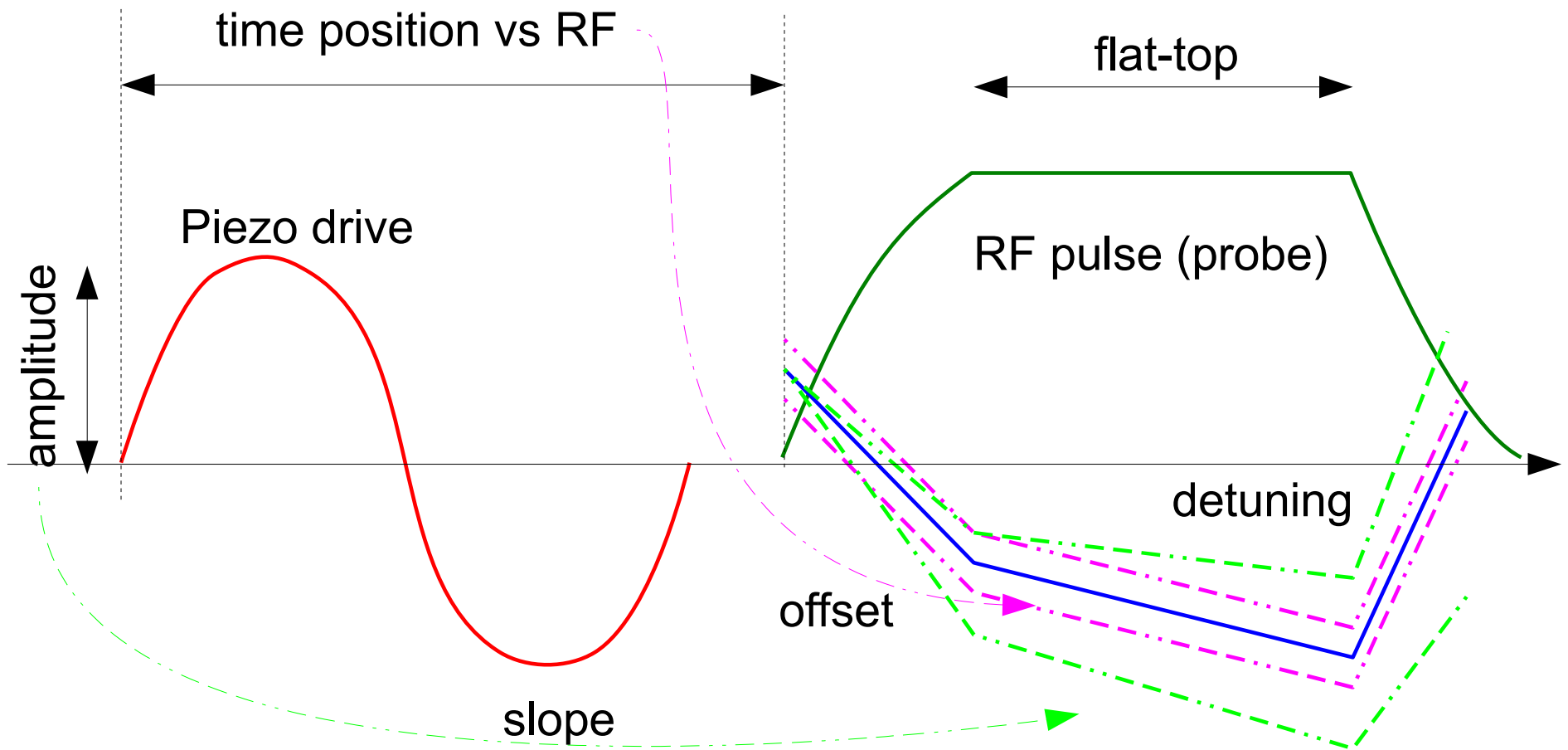
ACC6 (SP = 20 MV/m, rep = 5 Hz)



Reduction of reflected power



Piezo Driving Pulse



Piezo Control Panel

piezo_ctl_acc6: TTF2.RF/LLRF.DSP/ACC4_6/

Piezo Timing

PIEZO CONTROL SYSTEM – OPERATOR PANEL ACC6

ON/OFF

| | Freq[Hz] | No.Pulses | Delay[ms] | Amp[V/100] | Grad[MV/m] | Detn_FT[Hz] |
|----------|------------|-----------|-----------|------------|------------|-------------|
| DetnCav1 | Cav1 + 250 | + 1 | + 198.00 | - 0.55 | 32.9 | -12.37 |
| DetnCav2 | Cav2 + 250 | + 1 | + 198.04 | - 0.52 | 32.5 | -9.657 |
| DetnCav3 | Cav3 + 250 | + 1 | + 198.15 | - 0.52 | 31.0 | -4.175 |
| DetnCav4 | Cav4 + 250 | + 1 | + 197.87 | - 0.49 | 33.4 | -8.602 |
| DetnCav5 | Cav5 + 250 | + 1 | + 0.00 | + 0.00 | 18.3 | 79.493 |
| DetnCav6 | Cav6 + 250 | + 1 | + 198.25 | - 0.24 | 19.5 | 5.5828 |
| DetnCav7 | Cav7 + 250 | + 1 | + 198.17 | - 0.39 | 24.5 | -3.601 |
| DetnCav8 | Cav8 + 250 | + 1 | + 198.27 | - 0.39 | 23.4 | -13.56 |

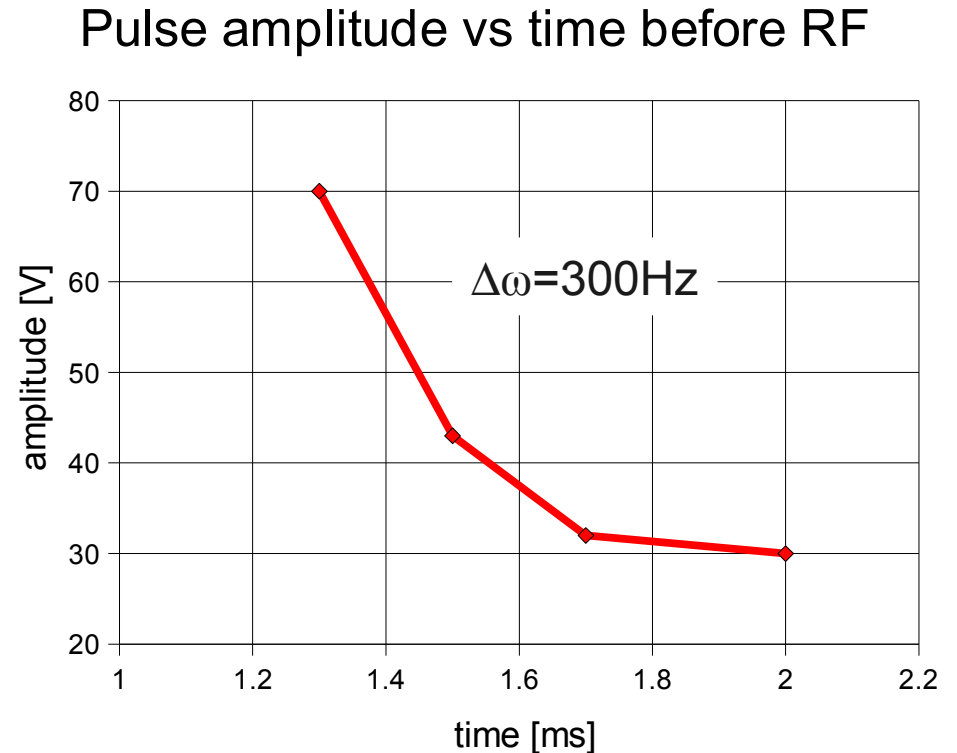
filling [us] 680

flattop [us] 1190

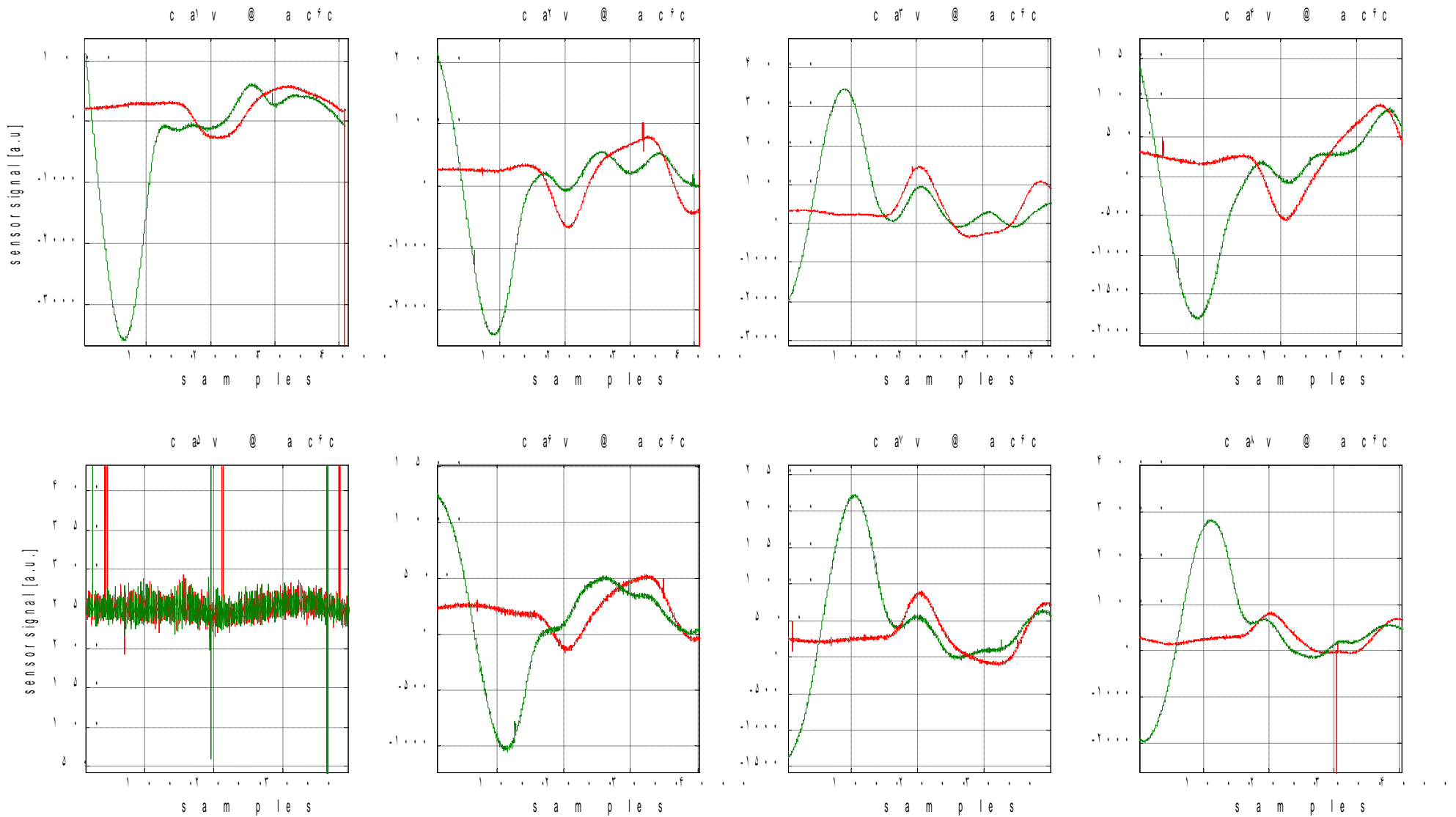
Calibration

Microphonics

- Due to limited speed of acoustic wave propagation through the cavity it is not possible to react within the RF pulse for variable microphonics
- Microphonics must be measured in advance (before RF pulse - either second piezo used as a sensor of some RF must be present before the pulse) and compensated as soon as possible



Piezo sensors in ACC6

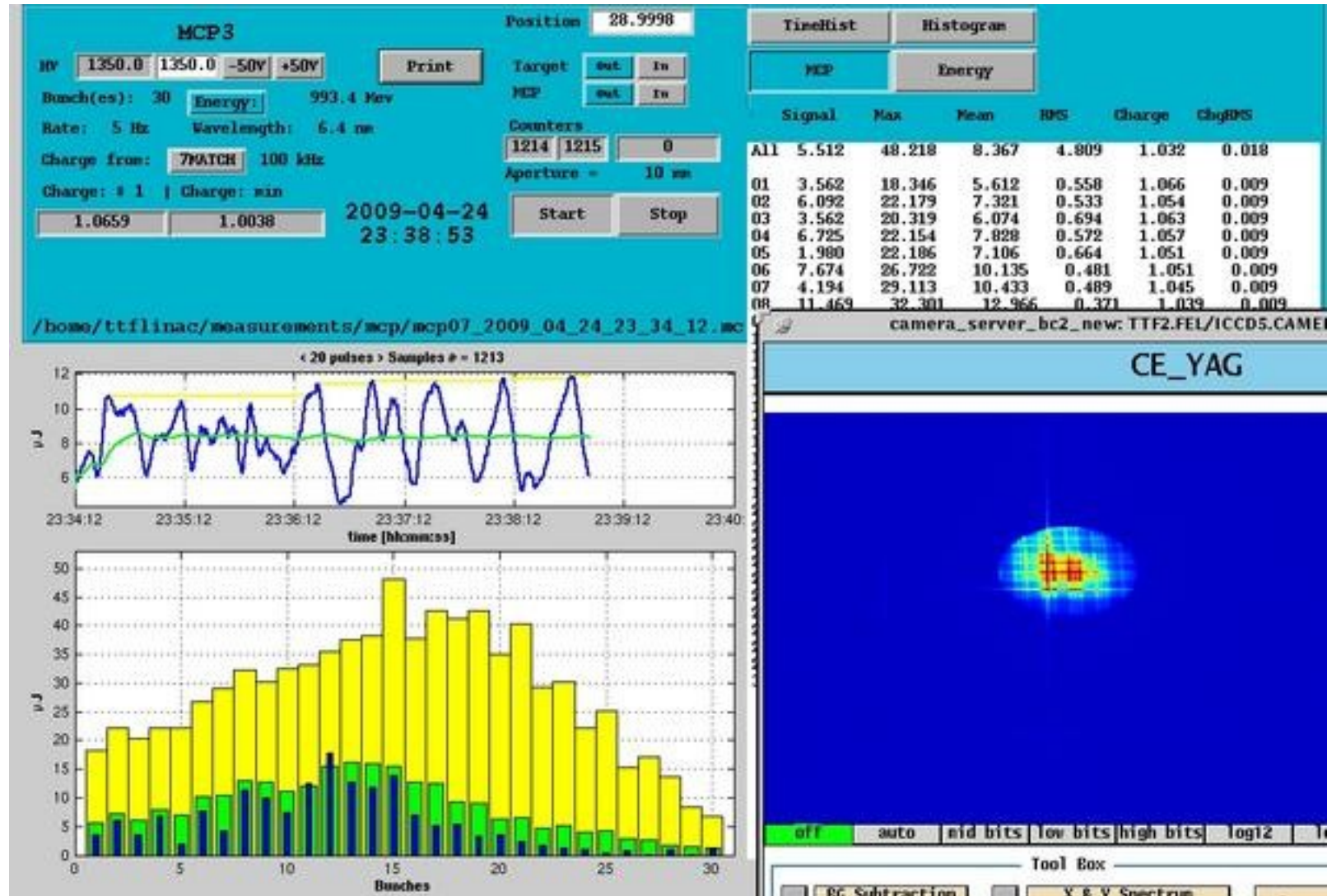


— Without piezo drive

— With piezo drive



Piezo operation influence on SASE level



ATCA integration

- Advantages:
 - No need for separate piezo crate (place, crate, power supply etc.)
 - The control link through the backplane
- Bigger form factor than Eurocard (2.5 more space) allows to integrate in the single board 16 channel piezo driver together with DACs and ADCs, probably it is also possible to put DC/DC converter (48V -> $\pm 100\text{V}$) in the board
- Special care for piezo connectors (high voltage, backside connection through customized RTM)

Conclusion

- Fast tuners with piezos are installed at FLASH and are operable.
- Piezo control system was developed and implemented. It is able to control piezos in 4 modules (32 cavities) simultaneously
- Commissioning of the piezo control system is in progress and will be continued after shutdown.
- The integration of piezo control in ATCA looks possible and promising.

Thank you for your attention



LLRF09 KEK, 18-21.10.2009

M.Grecki, DESY —